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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Tsuyoshi TAKAHASHI, et al.

SERIAL NO.: NEW U.S. PCT APPLICATION

FILED: HERewith

INTERNATIONAL APPLICATION NO.: PCT/JP05/06158

INTERNATIONAL FILING DATE: March 30, 2005

FOR: METHOD AND APPARATUS FOR FORMING METAL SILICATE FILM, AND
METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE

REQUEST FOR PRIORITY UNDER 35 U.S.C. 119
AND THE INTERNATIONAL CONVENTION

Commissioner for Patents
Alexandria, Virginia 22313

Sir:

In the matter of the above-identified application for patent, notice is hereby given that the applicant claims as priority:

<u>COUNTRY</u>	<u>APPLICATION NO</u>	<u>DAY/MONTH/YEAR</u>
Japan	2004-105300	31 March 2004

Certified copies of the corresponding Convention application(s) were submitted to the International Bureau in PCT Application No. PCT/JP05/06158. Receipt of the certified copy(s) by the International Bureau in a timely manner under PCT Rule 17.1(a) has been acknowledged as evidenced by the attached PCT/IB/304.

Respectfully submitted,
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